

Title (en)  
GAS INLET FOR AN ION SOURCE

Title (de)  
GASEINLASS FÜR EINE IONENQUELLE

Title (fr)  
DISPOSITIF D'ADMISSION DE GAZ POUR SOURCE D'IONS

Publication  
**EP 1082749 A2 20010314 (DE)**

Application  
**EP 99925006 A 19990518**

Priority  
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• EP 9903420 W 19990518

Abstract (en)  
[origin: US6646253B1] In a gas inlet structure for an ion source, including a capillary for the admission of a sample gas, which capillary is disposed in a guide tube for discharging a sample gas into the guide tube, the guide tube has an open end disposed in the ion source. The guide tube includes a valve for the pulsed admission of a carrier gas to the guide tube. The guide tube, the valve and the capillary are supported in a sealed support housing from which the guide tube with the capillary disposed therein projects into the ion source for supplying thereto the sample gas in a pulsed manner.

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**H01J 49/04**

IPC 8 full level  
**H01J 49/04** (2006.01)

CPC (source: EP US)  
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